

IN THE CLAIMS:

Claims 2-11, 13, 14, and 18-22 have been amended herein. All of the pending claims 1 through 22 are presented below. This listing of claims will replace all prior versions and listings in the application. Please enter these claims as amended.

1. (Original) A manufacturing process for forming a barrier layer comprising: providing a polysilicon plug having a surface in a portion of a dielectric layer of a portion of an integrated circuit;

depositing a layer of titanium on at least a portion of the surface of the polysilicon plug;

depositing a layer of amorphous material on at least a portion of the layer of titanium; and

depositing a layer of titanium nitride on at least a portion of the layer of amorphous material.

2. (Currently Amended) The ~~method process~~ of claim 1, further comprising:

forming a recess in a portion of the polysilicon plug; and

forming a well including a portion of the dielectric layer above the polysilicon plug;

depositing portions of the layer of titanium, the layer of amorphous material, and the layer of

titanium nitride within the well and over at least a portion of a surface of the dielectric layer; and

removing at least a portion of each of the layer of titanium, the layer of amorphous material, and

the layer of titanium nitride deposited ~~on~~ over the at least a portion of the surface of the dielectric layer.

3. (Currently Amended) The ~~method process~~ of claim 1, further comprising:

placing the dielectric layer of ~~an~~ the integrated circuit in a low-pressure chemical vapor deposition chamber;

providing a carrier atmosphere in the low-pressure chemical vapor deposition chamber having a pressure in a ~~range~~ range of between about 0.1 Torr ~~to~~ and about 100 Torr;

providing a precursor compound in the low-pressure chemical vapor deposition chamber; and

heating the dielectric layer to a temperature in a range of between about 200°C ~~to~~ and about 600°C.

4. (Currently Amended) The ~~method~~ process of claim 3, wherein the carrier atmosphere comprises a mixture including at least one gas selected from a group consisting of a noble gas, nitrogen and hydrogen.

5. (Currently Amended) The ~~method~~ process of claim 3, wherein the precursor compound comprises an organo-metallic compound.

6. (Currently Amended) The ~~method~~ process of claim 5, wherein the precursor compound comprises tetrakis-dialkylamido-titanium.

7. (Currently Amended) The ~~method~~ process of claim 2, wherein ~~the~~ removing the at least a portion of each of the layer of titanium, the layer of amorphous material, and the layer of titanium nitride deposited ~~on~~ over the at least a portion of the surface of the dielectric layer comprises planarizing the dielectric layer to remove at least the portions of the layer of titanium, the layer of amorphous material, and the layer of titanium nitride deposited ~~on~~ over the at least a portion of the surface of the dielectric layer.

8. (Currently Amended) The ~~method~~ process of claim 1, wherein ~~the~~ depositing the layer of amorphous material comprises depositing a layer of titanium carbonitride having an amorphous structure substantially without grain boundaries therein.

9. (Currently Amended) The ~~method~~ process of claim 1, wherein ~~the~~ depositing the layer of amorphous material comprises depositing a layer of substantially amorphous material substantially without crystal grain boundaries therein.

10. (Currently Amended) The method process of claim 8, wherein the depositing the layer of titanium carbonitride comprises depositing a layer of titanium carbonitride having a ratio of carbon to nitrogen therein in the range of from about 1:5 to about 1:20.

11. (Currently Amended) The method process of claim 6, wherein the precursor compound comprises a sole precursor.

12. (Original) A method for forming a barrier layer comprising:
providing a polysilicon plug having a surface in a portion of a dielectric layer of a circuit;
depositing a layer of titanium on at least a portion of the surface of the polysilicon plug;
depositing a layer of amorphous material on at least a portion of the layer of titanium; and
depositing a layer of titanium nitride on at least a portion of the layer of amorphous material.

13. (Currently Amended) The method of claim 12, further comprising:
forming a recess in a portion of the polysilicon plug; and
forming a well including a portion of the dielectric layer above ~~and~~ the recess in the portion of the polysilicon plug;
depositing portions of the layer of titanium, the layer of amorphous material, and the layer of titanium nitride within the well and over at least a portion of a surface of the dielectric layer; and
removing at least a portion of each of the layer of titanium, the layer of amorphous material, and the layer of titanium nitride deposited ~~on~~ over the at least a portion of the surface of the dielectric layer.

14. (Currently Amended) The method of claim 12, further comprising:
placing the dielectric layer of ~~an integrated~~ the circuit in a low-pressure chemical vapor deposition chamber;

providing a carrier atmosphere in the low-pressure chemical vapor deposition chamber having a pressure in a ~~range~~ range of between about 0.1 Torr ~~to~~ and about 100 Torr; providing a precursor compound in the low-pressure chemical vapor deposition chamber; and heating the dielectric layer to a temperature in a range of between about 200°C ~~to~~ and about 600°C.

15. (Original) The method of claim 14, wherein the carrier atmosphere comprises a mixture including at least one gas selected from a group consisting of a noble gas, nitrogen and hydrogen.

16. (Original) The method of claim 14, wherein the precursor compound comprises an organo-metallic compound.

17. (Original) The method of claim 16, wherein the precursor compound comprises tetrakis-dialkylamido-titanium.

18. (Currently Amended) The method of claim 13, wherein ~~the~~ removing the at least a portion of each of the layer of titanium, the layer of amorphous material, and the layer of titanium nitride deposited ~~on~~ over the at least a portion of the surface of the dielectric layer includes planarizing the dielectric layer to remove at least the portions of the layer of titanium, the layer of amorphous material, and the layer of titanium nitride deposited ~~on~~ over the at least a portion of the surface of the dielectric layer.

19. (Currently Amended) The method of claim 12, wherein ~~the~~ depositing the layer of amorphous material comprises depositing a layer of titanium carbonitride having an amorphous structure substantially without grain boundaries therein.

20. (Currently Amended) The method of claim 12, wherein the depositing the layer of amorphous material comprises depositing a layer of substantially amorphous material having few crystal grain boundaries therein.

21. (Currently Amended) The method of claim 19, wherein the depositing the layer of titanium carbonitride comprises depositing a layer of titanium carbonitride having a ratio of carbon to nitrogen therein in the range of from about 1:5 to about 1:20.

22. (Currently Amended) The process method of claim 14, wherein the precursor compound comprises a sole precursor.